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Attorney Docket # 5367-47

Patent

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Stefan BADER et al.

Serial No.: 10/696,882

Filed: October 30, 2003

For: Method for Depositing a Material on a Substrate
Wafer

Examiner:

Group Art:

I hereby certify that this correspondence is being
facsimile transmitted to the United States Patent &
Trademark Office on:December 14, 2005
(Date of Transmission)(571) 273-8300
Facsimile No.Thomas Langer
Name of applicant, assignee or Registered Representative

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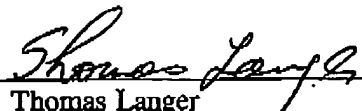
December 14, 2005
Date of SignatureCommissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450STATUS LETTER

S I R:

In reviewing our file in the above-identified patent application, we note that we have received no action since the filing of this application on **October 30, 2003**. We would therefore appreciate a report as to the status of this case at your earliest possible convenience.

Respectfully submitted,
COHEN, PONTANI, LIEBERMAN & PAVANE

By

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December 14, 2005